

ABSTRACT

Provided is a method for manufacturing a nonmagnetic substrate, the method including edge surface polishing processing for polishing an edge surface of a plate-like nonmagnetic substrate having a side wall surface and a chamfered surface formed between a main surface and the side wall surface. The edge surface polishing processing is processing for polishing the edge surface of the substrate by forming a magnetic field using a magnetic field generation means such that magnetic field lines advance in a thickness direction of the substrate, bringing the edge surface of the substrate and magnetic functional fluid into contact with each other in a state in which the magnetic functional fluid containing polishing abrasive particles is held by the magnetic field, and moving the substrate and the magnetic functional fluid relative to each other. Polishing abrasive particles are supplied to the magnetic functional fluid during the edge surface polishing processing.

[Fig. 6]